Special Issue

Metasurface-Based Devices and Systems

Message from the Guest Editors

Metasurfaces represent a groundbreaking approach to controlling electromagnetic waves, enabling unprecedented functionalities and so on. These two-dimensional structures, composed of subwavelength-scale elements, have become a cornerstone in modern photonics and optoelectronics, transforming applications in imaging, sensing, and beyond. We are pleased to announce this Special Issue dedicated to "Metasurface-Based Devices and Systems". We invite high-quality reviews, original research articles, and interdisciplinary contributions that address topics including but not limited to the following:

Design, simulation, and optimization of novel metasurfaces.

Applications in imaging, sensing, and communication technologies.

Advances in tunable, reconfigurable, and multifunctional metasurfaces.

Material innovations and scalable fabrication methods for metasurfaces.

Integration of metasurfaces into optoelectronic and photonic systems.

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Editor-in-Chief

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